

## Special Issue

# Recent Advances in Metal Oxide Thin Films and Nanostructures for Diverse Applications

### Message from the Guest Editor

We would like to invite you to submit your work to this Special Issue, focused on “Recent Advances in Metal Oxide Thin Films and Nanostructures for Diverse Applications”. This Special Issue aims to provide a snapshot of the state of the art in the preparations, characterizations, and applications of MO thin films and nanostructures. In particular, the topics of interest include, but are not limited to, the following:

- MO thin film growths and characterization techniques;
- Synthesis of MO nanostructures, properties, and applications;
- Nanomechanical properties of MO thin films and nanostructures studied by the nanoindentation technique;
- Photocatalytic degradation of pollutants and photoelectrochemical activity of MO thin films and nanostructures;
- Functional properties and applications of MO thin films and nanostructures (e.g., HER, fuel cells, solar cells, hard coatings, antimicrobial activity, anti-bacteria, photodetectors, sensing, electronic devices, optoelectronics, memories, etc.);
- Theory, modeling, atomistic simulation, and numerical analysis of MO thin films and nanostructures.

### Guest Editor

Dr. Phuoc Huu Le

1. Center for Plasma and Thin Film Technologies, Ming Chi University of Technology, New Taipei City 24301, Taiwan
2. Department of Physics and Biophysics, Can Tho University of Medicine and Pharmacy, Can Tho 94000, Vietnam

### Deadline for manuscript submissions

closed (30 November 2024)



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*Micromachines*  
Editorial Office  
MDPI, Grosspeteranlage 5  
4052 Basel, Switzerland  
Tel: +41 61 683 77 34  
[micromachines@mdpi.com](mailto:micromachines@mdpi.com)

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## About the Journal

### Message from the Editor-in-Chief

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### Editor-in-Chief

Prof. Dr. Ai-Qun Liu

1. Department of Electrical and Electronic Engineering, The Hong Kong Polytechnic University, Hong Kong, China
2. School of Electrical and Electronic Engineering, Nanyang Technological University, Singapore 639798, Singapore

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